



Inventor: NIISOE
Docket No.: 10873.1388US01
Title: METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE
Serial No.: 10/750,359
Sheet 1 of 14

FIG. 1A

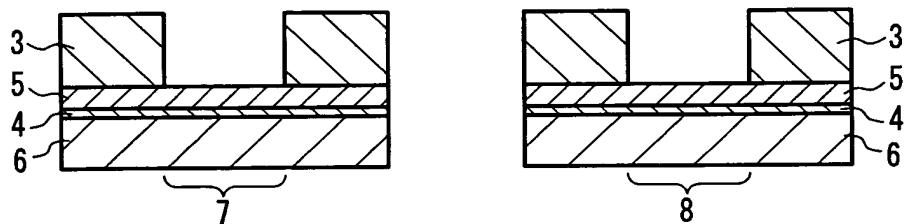


FIG. 1B

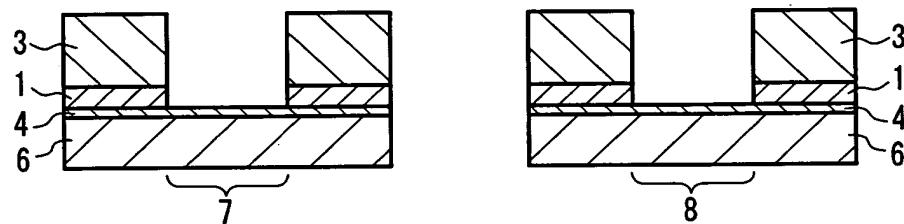


FIG. 1C

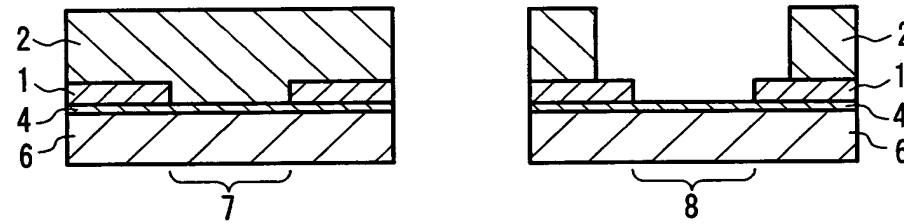


FIG. 1D

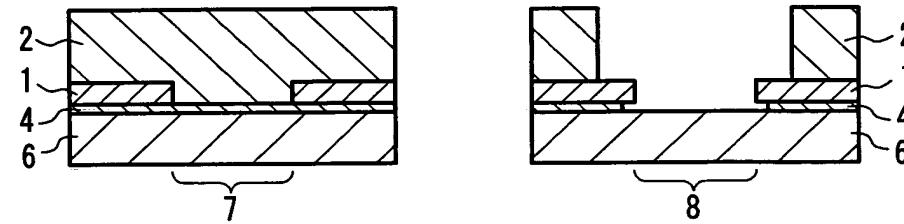


FIG. 2A

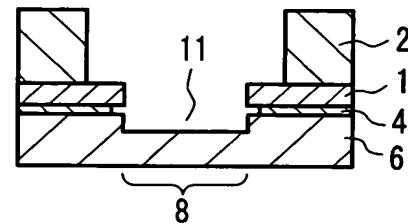
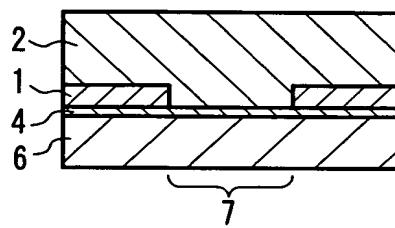


FIG. 2B

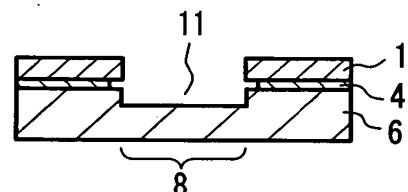
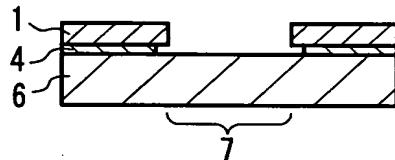


FIG. 2C

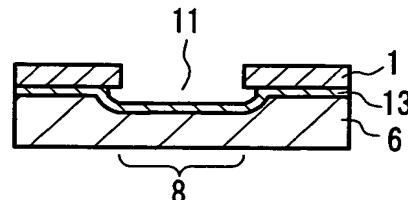
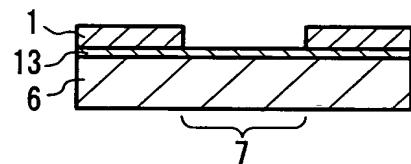


FIG. 2D

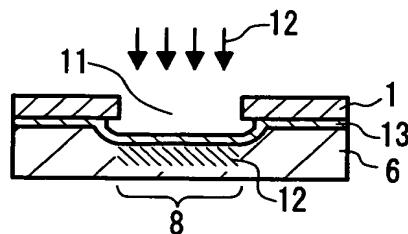
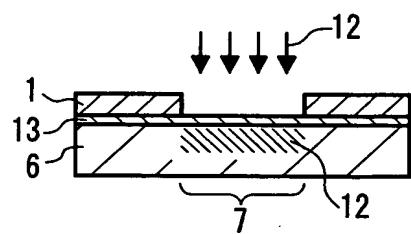
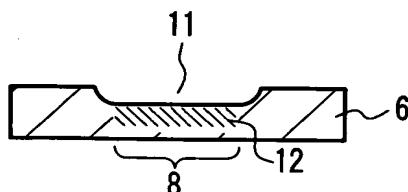
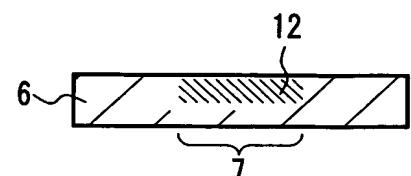


FIG. 2E



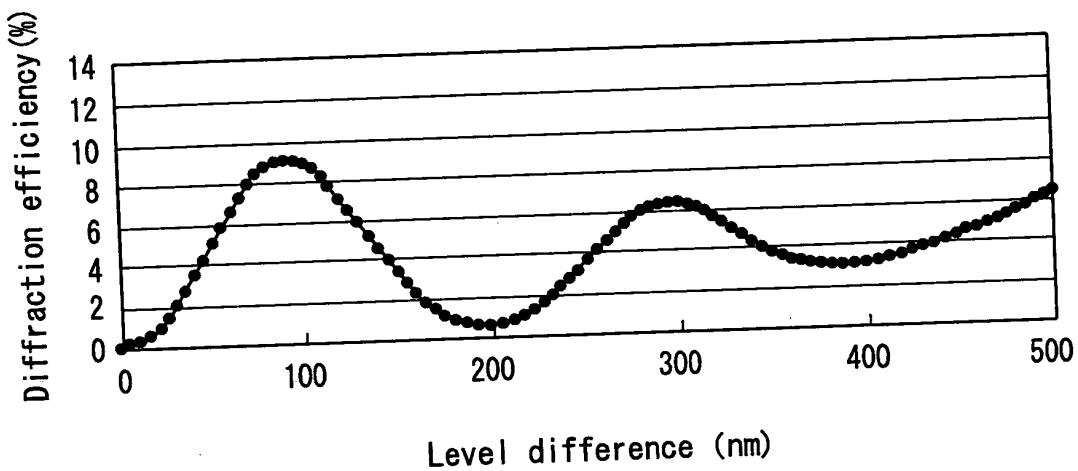


FIG. 3

FIG. 4A

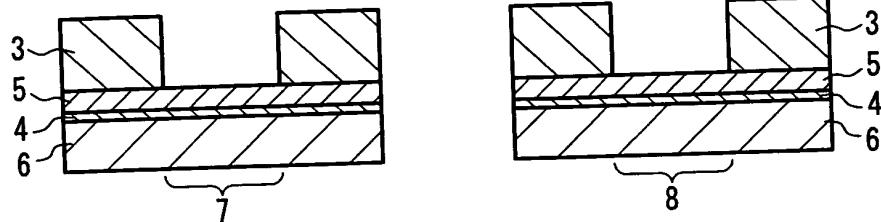


FIG. 4B

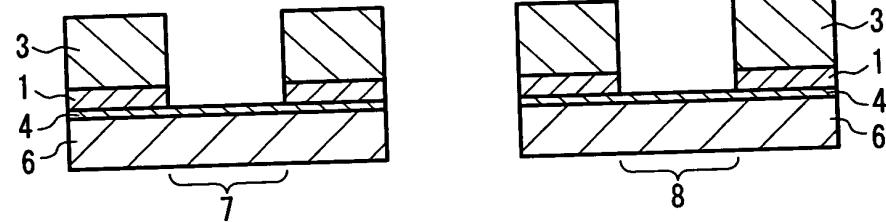


FIG. 4C

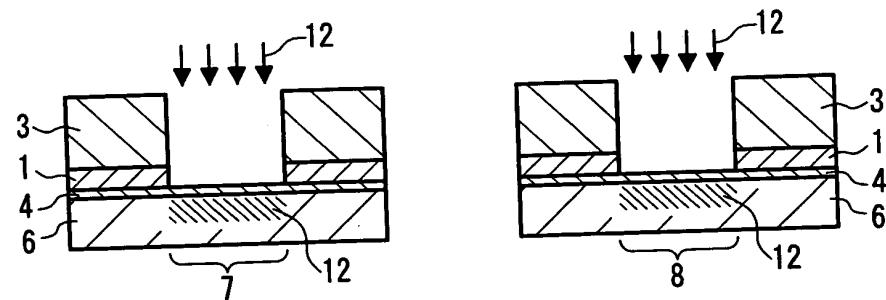


FIG. 4D

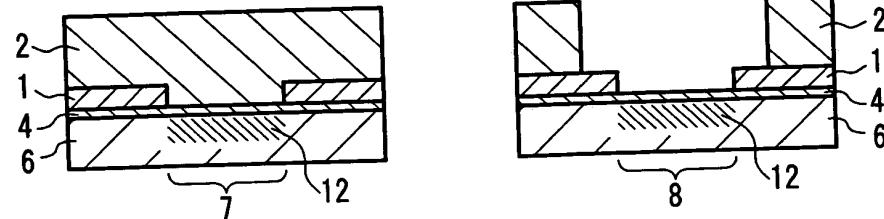


FIG. 5A

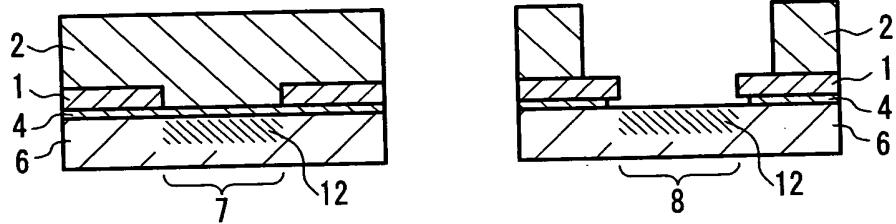


FIG. 5B

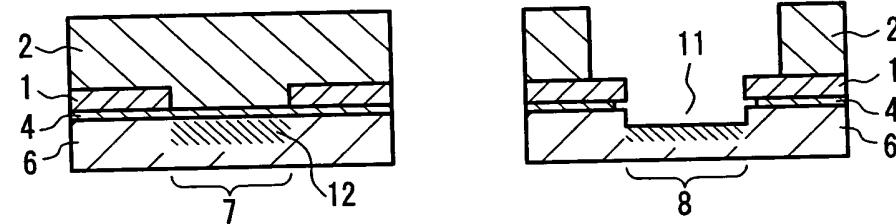


FIG. 5C

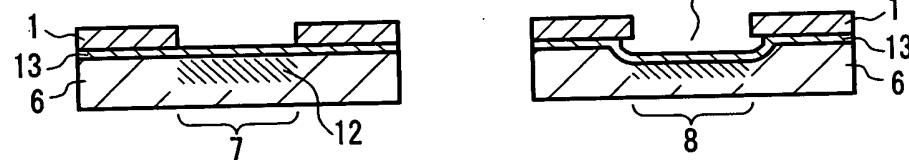


FIG. 5D

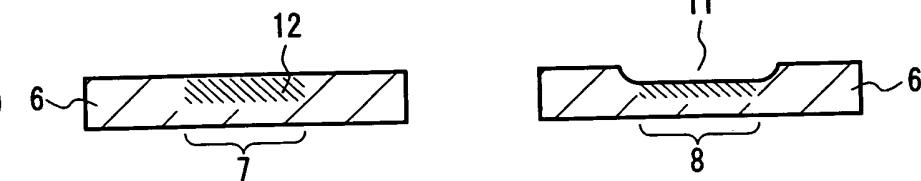


FIG. 6A

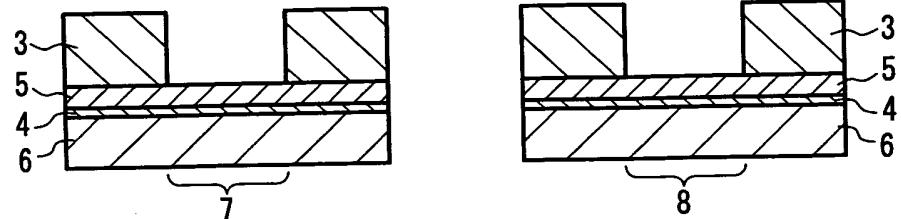


FIG. 6B

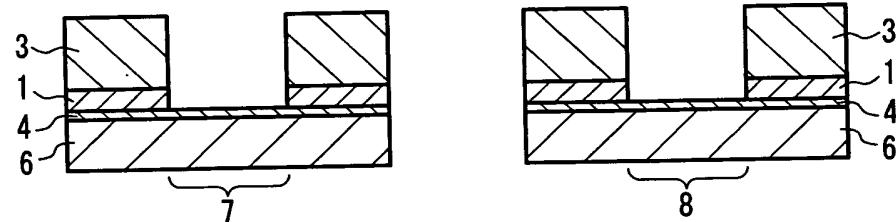


FIG. 6C



FIG. 6D

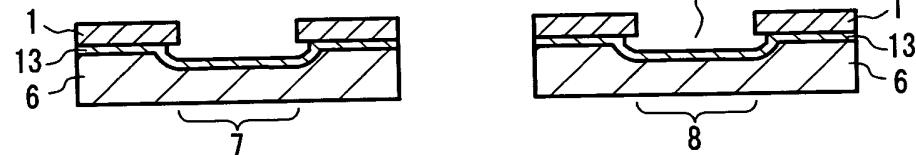


FIG. 6E

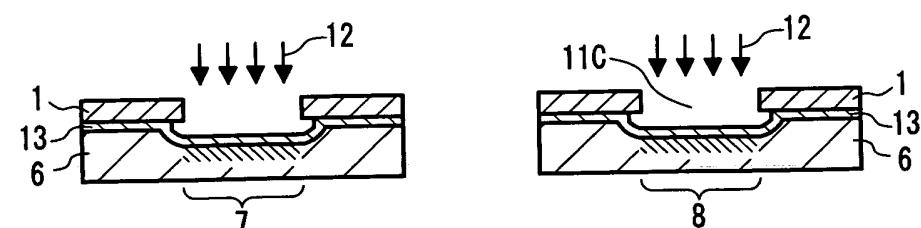
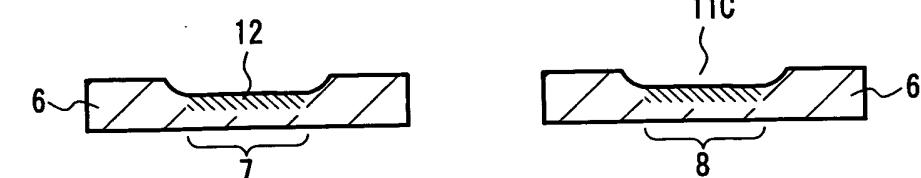


FIG. 6F



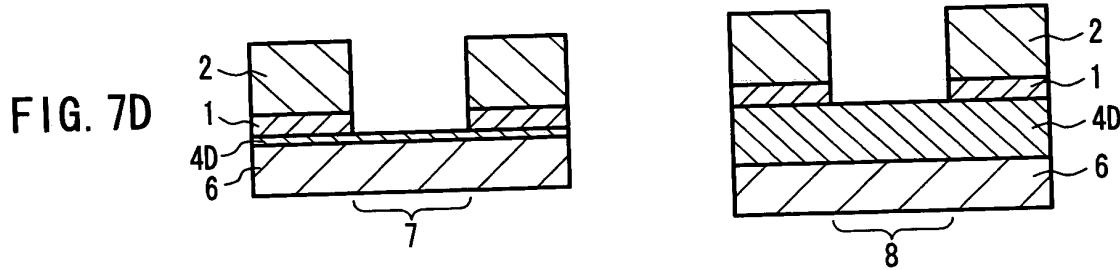
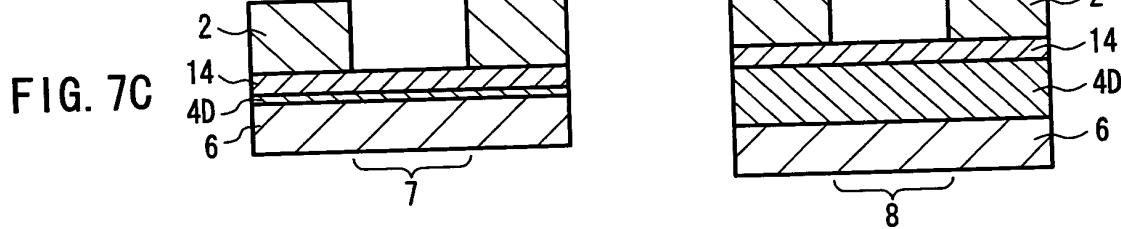
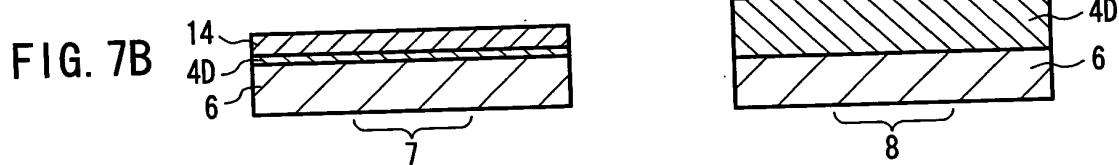
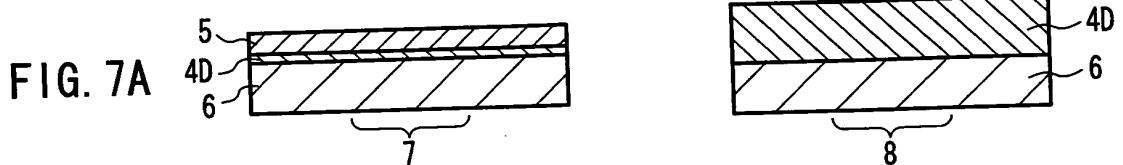


FIG. 8A

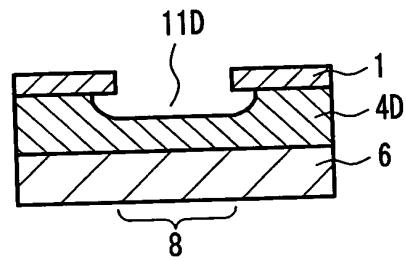
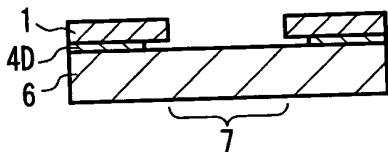


FIG. 8B

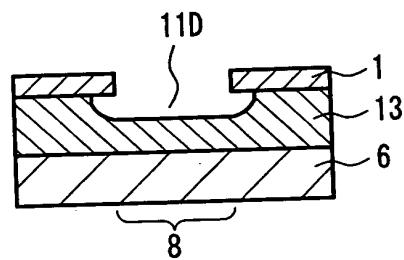
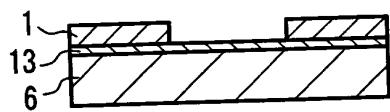


FIG. 8C

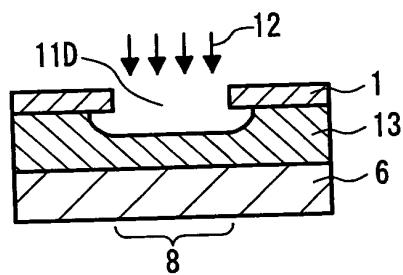
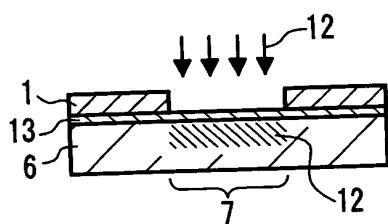


FIG. 8D

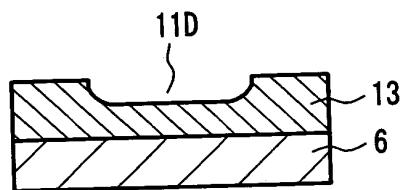
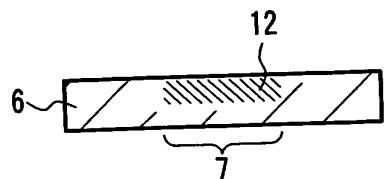


FIG. 9A

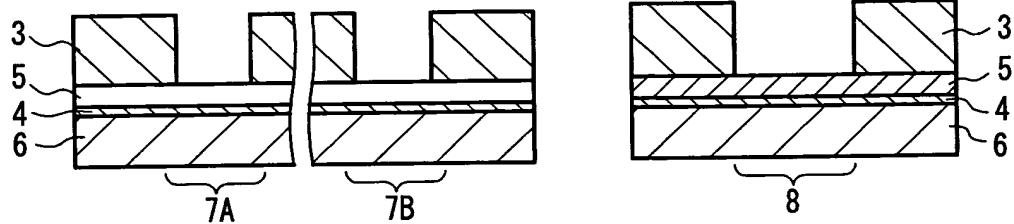


FIG. 9B

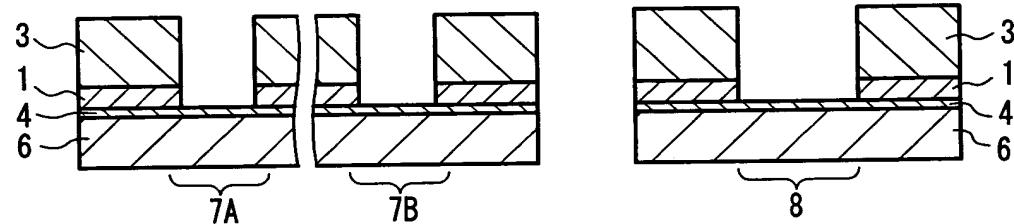


FIG. 9C

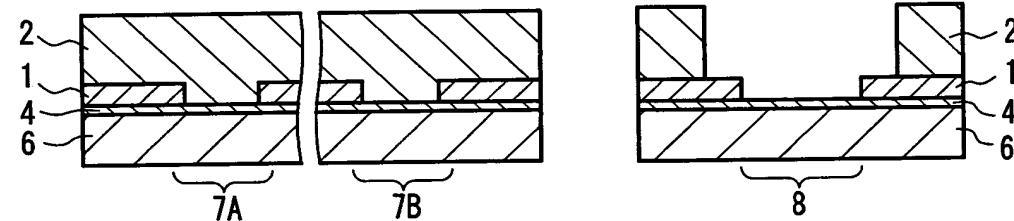


FIG. 9D

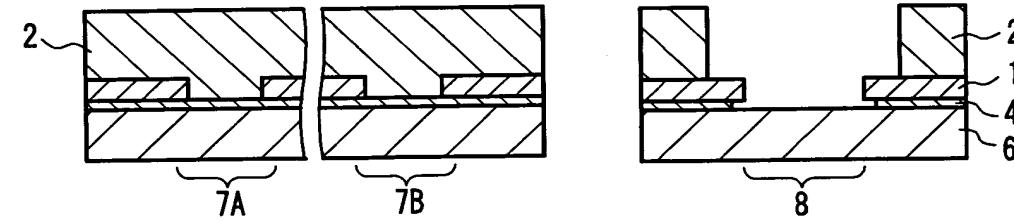
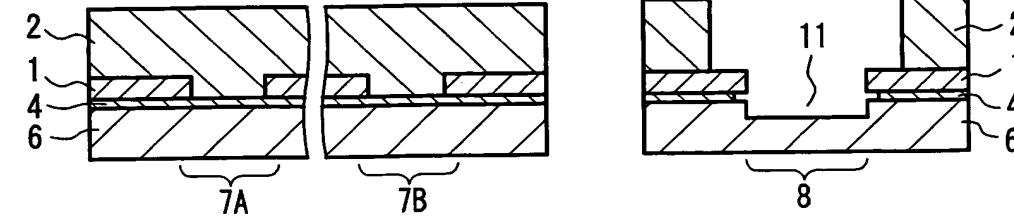


FIG. 9E



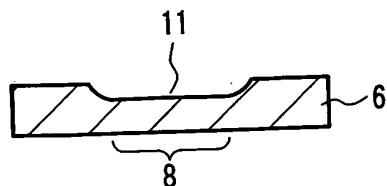
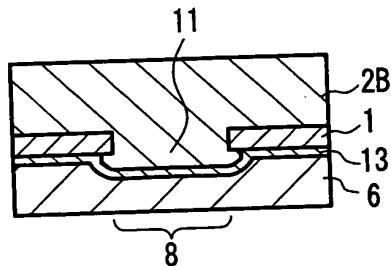
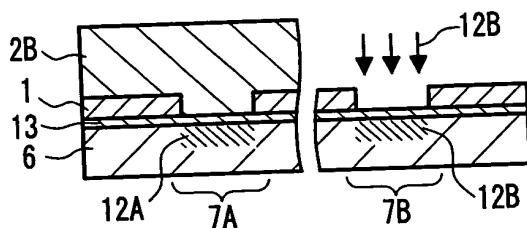
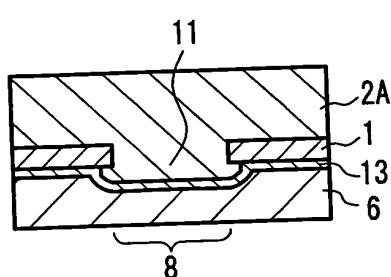
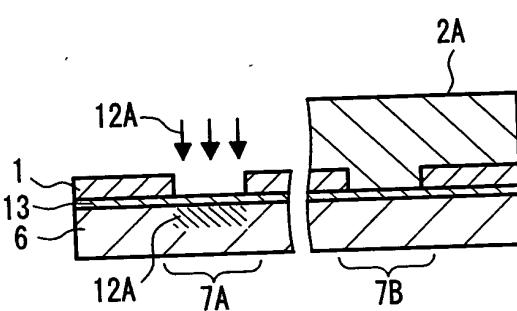
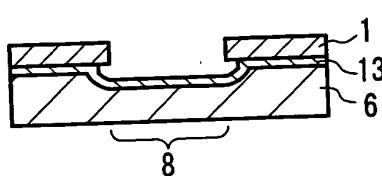
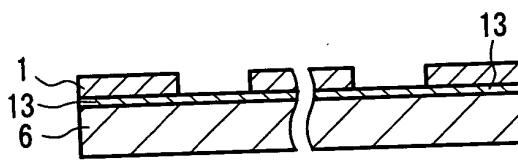
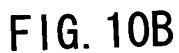
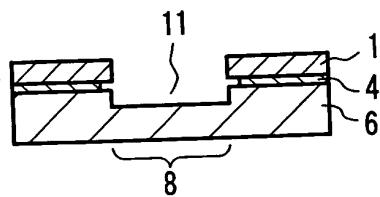
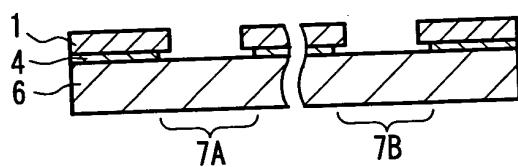


FIG. 11A
PRIOR ART

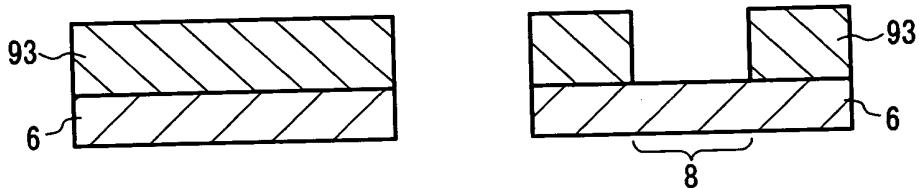


FIG. 11B
PRIOR ART

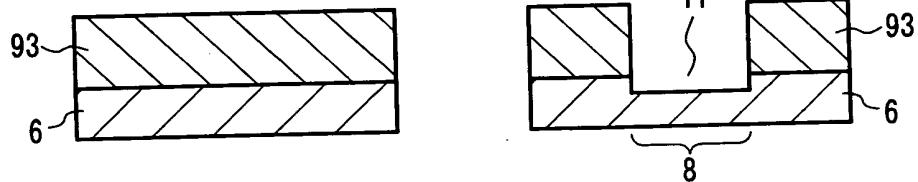


FIG. 11C
PRIOR ART

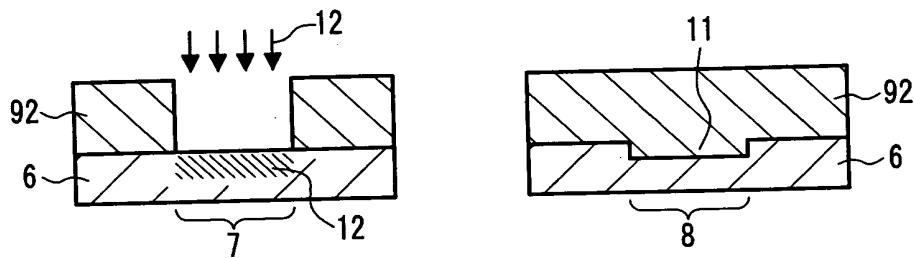


FIG. 11D
PRIOR ART

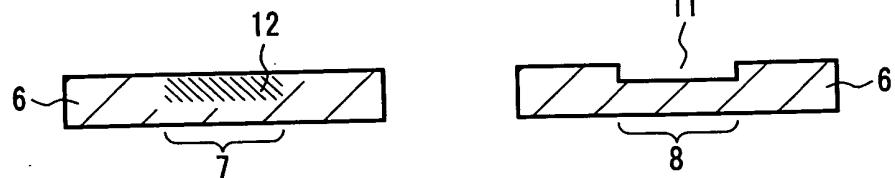


FIG. 12A
PRIOR ART

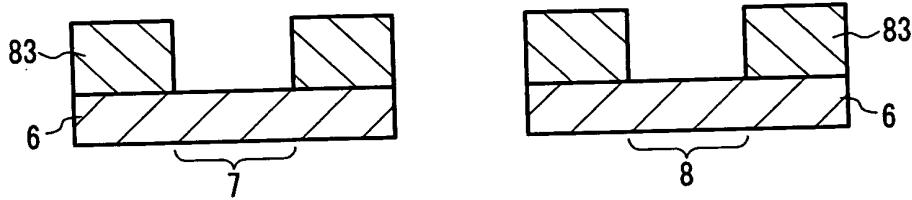


FIG. 12B
PRIOR ART

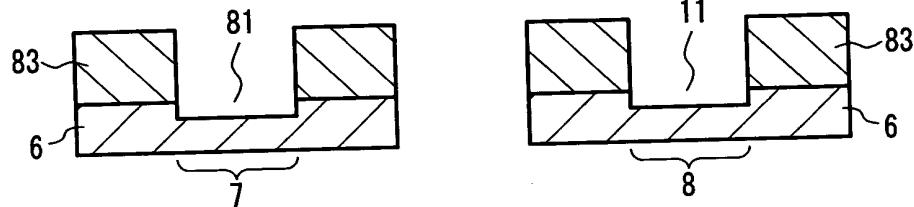


FIG. 12C
PRIOR ART

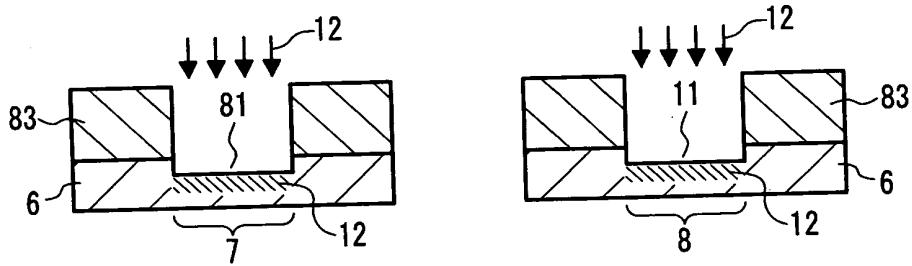


FIG. 12D
PRIOR ART

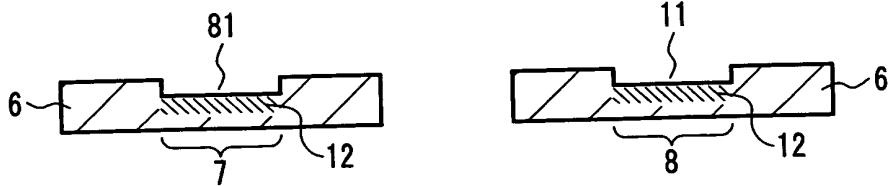


FIG. 13A
PRIOR ART

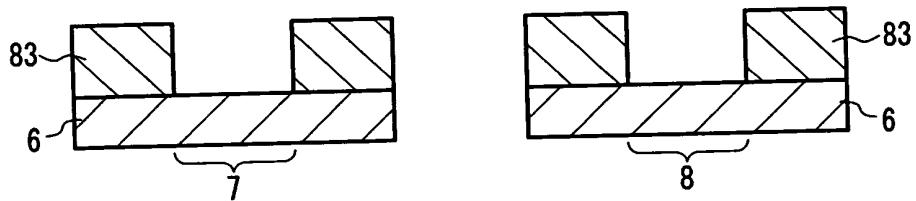


FIG. 13B
PRIOR ART

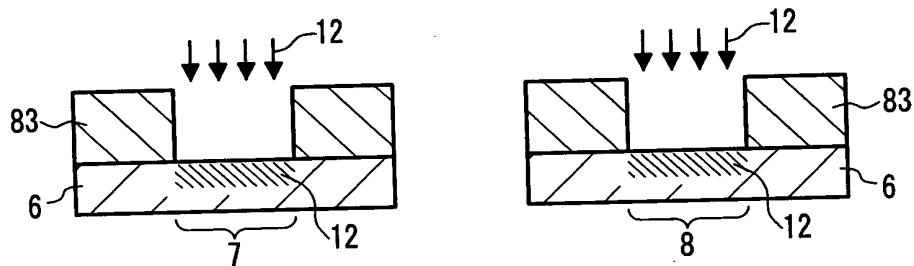


FIG. 13C
PRIOR ART

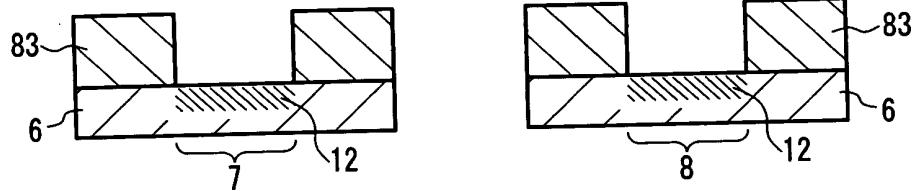


FIG. 13D
PRIOR ART

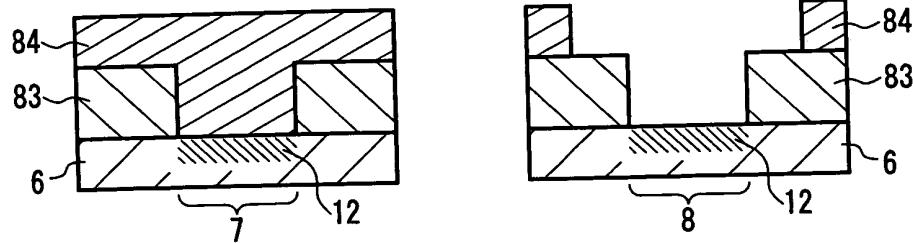


FIG. 14A
PRIOR ART

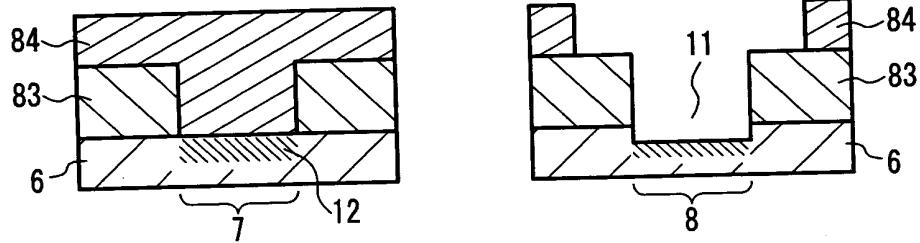


FIG. 14B
PRIOR ART

